

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: )  
)  
Hajime NAGANO et al. )  
) Group Art Unit:  
Serial No.: Not Yet Assigned )  
) Examiner:  
Filed: October 2, 2003 )  
)  
For: SEMICONDUCTOR DEVICE )  
AND METHOD FOR )  
MANUFACTURING PARTIAL )  
SOI SUBSTRATES )

**Commissioner for Patents**  
**P.O. Box 1450**  
**Alexandria, VA 22313-1450**  
**MAIL STOP: PATENT APPLICATION**

Sir:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)**

Pursuant to 37 C.F.R. §§1.56 and 1.97(b), applicants bring to the Examiner's attention the document listed on attached Form PTO-1449. A copy of the listed document is attached. Applicants respectfully request that the Examiner consider the document listed on attached Form PTO-1449 and indicate that it was considered by making an appropriate notation on this form.

This Information Disclosure Statement is being filed with the above-referenced application.

The following is a concise statement of relevance of the non-English language documents:

FINNEGAN  
HENDERSON  
FARABOW  
GARRETT &  
DUNNER LLP

1300 I Street, NW  
Washington, DC 20005  
202.408.4000  
Fax 202.408.4400  
www.finnegan.com

1. Japanese Patent Laid Open (KOKAI) PH11-150182 discloses the process and structure of SIMOX-SOI wafer having both SOI and bulk regions. The stress-relaxation region, for example a shallow trench isolation region, was formed at the boundary of SOI region and the bulk region before the implantation of oxygen.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that the listed document is material or constitute "prior art." If the Examiner applies the document as prior art against any claim in the application and applicants determine that the cited document does not constitute "prior art" under United States law, applicants reserve the right to present to the office the relevant facts and law regarding the appropriate status of such document. Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed document, should the document be applied against the claims of the present application.

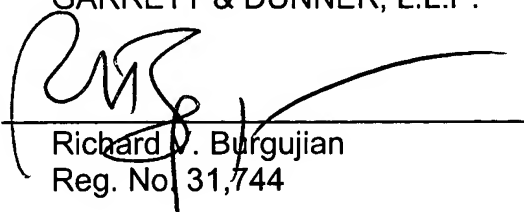
If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

Dated: October 2, 2003

By:

  
Richard V. Burgujian  
Reg. No. 31,744

Enclosures  
RVB/FPD/peg

FINNEGAN  
HENDERSON  
FARABOW  
GARRETT &  
DUNNER LLP  
1300 I Street, NW  
Washington, DC 20005  
202.408.4000  
Fax 202.408.4400  
www.finnegan.com

## INFORMATION DISCLOSURE CITATION

Atty. Docket No.	04329.3157	Serial No.	
Applicant	Hajime NAGANO et al.		
Filing Date	October 2, 2003	Group:	

U.S. PATENT DOCUMENTS							
Examiner Initial*		Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate

FOREIGN PATENT DOCUMENTS							
		Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
		11-150182	6/2/99	Japan			No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	

Examiner	Date Considered
<p>*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>	
Form PTO 1449	Patent and Trademark Office - U.S. Department of Commerce